

The listing of claims will replace all prior versions, and listings, of claims in the application:

Listing of Claims:

1. (Currently Amended) A method of manufacturing a semiconductor device comprising steps of:

~~irradiating a linear laser beam to a surface of a semiconductor with a line-shaped laser beam~~ in a gas atmosphere containing an impurity ~~while scanning the linear laser beam;~~

applying an electromagnetic energy to the gas atmosphere so as to decompose the gas atmosphere containing the impurity while irradiating the surface with the ~~linear line-shaped~~ laser beam; ~~[[and]]~~

changing a relative position of the semiconductor with respect to the line-shaped laser beam while irradiating the surface with the line-shaped laser beam; and

heating the semiconductor at a temperature not higher than a crystallization temperature of said semiconductor while applying the electromagnetic energy.

2. (Currently Amended) The method according to claim 1 wherein the gas atmosphere comprises a gas selected from the group consisting of AsH_3 , PH_3 , BF_3 , BCl_3 and $\text{B}(\text{CH}_3)_3$ $\text{B}(\text{CH}_3)_3$.

3. (Canceled)

4. (Currently Amended) A method of manufacturing a semiconductor device comprising steps of:

~~providing~~ disposing a substrate in a chamber, said substrate having a semiconductor film comprising silicon formed thereon ~~over a substrate in a chamber;~~

~~transferring the substrate in a first direction;~~
introducing a gas containing an impurity ~~a dopant species~~ into the chamber;
irradiating the semiconductor film with a laser light through a window having a slit shape while ~~transferring the substrate so that the dopant species~~ changing a relative position of the substrate with respect to the laser light so that the impurity is introduced into the semiconductor film; and
heating the semiconductor film during a laser light irradiation.

6 ~~5.~~ (Original) The method of claim 4 wherein the semiconductor film is heated not lower than 200 degree C.

9 ~~6.~~ (Currently Amended) A method of manufacturing a semiconductor device comprising steps of:

disposing a substrate in a chamber, said substrate providing having a
semiconductor film comprising silicon formed thereon ~~over a substrate in a chamber;~~
~~transferring the substrate in a first direction;~~
introducing a gas containing an impurity ~~a dopant species~~ into the chamber;
applying an electromagnetic energy to the gas in the chamber in order to activate the gas; and
irradiating the semiconductor film with a laser light through a window having a slit shape while ~~transferring the substrate so that the dopant species~~ so that the impurity is introduced into the irradiated portion of the semiconductor film; and
changing a relative position of the substrate with respect to the laser light while
irradiating the semiconductor film with the laser light.

10 ~~7.~~ (Currently Amended) The method according to claim 6 further comprising heating the semiconductor film during ~~a laser light irradiation~~ the irradiation of the laser light.

13 8. (Currently Amended) A method of manufacturing a semiconductor device comprising steps of:

- holding a ~~substrate~~ semiconductor in a chamber;
- introducing a gas containing ~~dopant-species~~ an impurity into the chamber;
- producing a plasma of said gas by applying an electromagnetic energy;
- introducing said ~~dopant-species~~ impurity from said plasma into an entirety of a line-shaped target portion of said ~~substrate~~ semiconductor;
- changing a relative position of the ~~substrate~~ line-shaped target portion with respect to said semiconductor in said chamber; and
- heating the semiconductor at a temperature not higher than a crystallization temperature of said semiconductor while applying the electromagnetic energy.

9.-10. (Canceled)

14 11. (Original) The method according to claim 8 wherein said gas is selected from the group consisting of PH_3 and B_2H_6 .

15 12. (Original) The method according to claim 8 wherein said gas is selected from the group consisting of AsH_3 , PH_3 , BF_3 , BCl_3 , and $\text{B}(\text{CH}_3)_3$.

18 13. (Currently Amended) A method of manufacturing a semiconductor device comprising steps of:

- producing a plasma of a gas by applying an electromagnetic energy, wherein said gas contains ~~dopant-species~~ an impurity;
- introducing said ~~dopant-species~~ impurity from said plasma into an entirety of a line-shaped target portion of a semiconductor film;

changing a relative position of the line-shaped target portion ~~[[over]]~~ with respect
to the semiconductor film; and

heating the semiconductor film at a temperature not higher than a crystallization
temperature of said semiconductor film while applying the electromagnetic energy.

14.-15. (Canceled)

~~18~~ 16. (Original) The method according to claim 13 wherein said gas is selected
from the group consisting of PH_3 and B_2H_6 .

~~19~~ 17. (Original) The method according to claim 13 wherein said gas is selected
from the group consisting of AsH_3 , PH_3 , BF_3 , BCl_3 , and $\text{B}(\text{CH}_3)_3$.

~~20~~ 18. (Original) The method according to claim 13 wherein said semiconductor
device includes a thin film transistor.

~~3~~ 19. (New) The method according to claim 1 wherein said semiconductor device
includes a thin film transistor.

~~7~~ 20. (New) The method according to claim 4 wherein said semiconductor device
includes a thin film transistor.

~~11~~ 21. (New) The method according to claim 6 wherein said semiconductor device
includes a thin film transistor.

~~16~~ 22. (New) The method according to claim 8 wherein said semiconductor device
includes a thin film transistor.

41 23. (New) The method according to claim 1 wherein the semiconductor is moved with respect to the line-shaped laser beam.

8 24. (New) The method according to claim 4 wherein the substrate is moved with respect to the laser light.

12 25. (New) The method according to claim 6 wherein the substrate is moved with respect to the laser light.